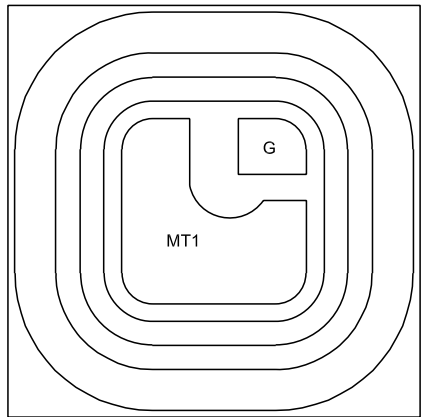


**PROCESS DETAILS**

|                        |                       |
|------------------------|-----------------------|
| Process                | Glass Passivated Mesa |
| Die Size               | 57 x 57 MILS          |
| Die Thickness          | 8.6 MILS ± 0.6 MILS   |
| MT1 Bonding Pad Area   | 28 x 16 MILS          |
| Gate Bonding Pad Area  | 10 x 9 MILS           |
| Top Side Metalization  | Al - 45,000Å          |
| Back Side Metalization | Al/Mo/Ni/Ag - 32,000Å |

**GEOMETRY**



BACKSIDE MT2

R0

**GROSS DIE PER 4 INCH WAFER**

3,374

**PRINCIPAL DEVICE TYPES**

CQ92-2M  
CQ223-2M  
CQ89-2M

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R0 (29 -March 2005)